**Safety and work protocol Estrelas:**

* Confirm that the workspace is clean.
* Before starting the process, make sure the top plate is at 160 °C and the chamber heater is at 120 °C.
* Carrier is only 4’’ Si wafer (500um thick, flat) with SiO2 layer.
* Do not insert metal and tapes.
* Make sure to load sample with a material that is approved.
* Small Sample (max 3’’) should be properly glued with Fomblin oil
* During the process, ensure all parameters are stable (Forward power, helium flow, gas flow, ....).
* Don’t run a manual process.

For any questions, call 79812/ 08-6479812 Tania



For any problems